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1/1

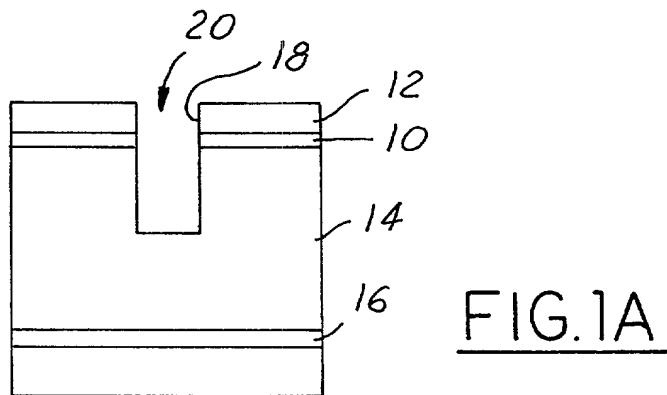


FIG.1A

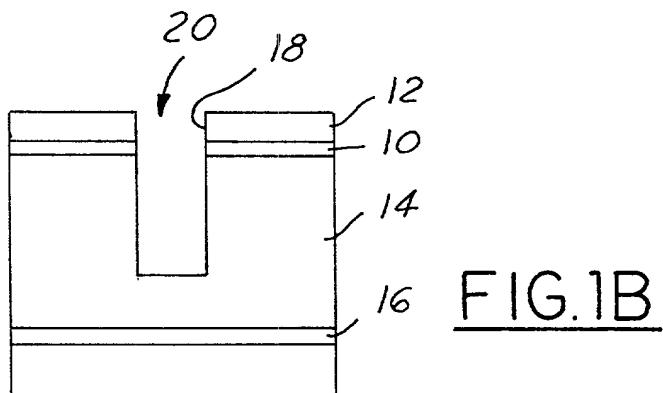


FIG.1B

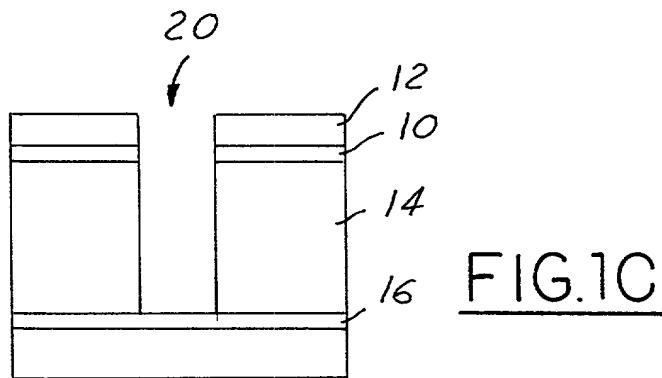


FIG.1C